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Serial No.: 10/550,855

§ Filing Date: 18 September 2006

Title: FORMATION OF THIN SEMI-
CONDUCTOR LAYERS BY LOW-
ENERGY PLASMA ENHANCED
CHEMICAL VAPOR DEPOSITION -
AND SEMICONDUCTOR
HETEROSTRUCTURE DEVICES

§ Examiner: MCCALL SHEPARD, Sonya D
§ Conf. No.: 3611
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Applicant: VON KAENEL, Hans

§ Atty Docket No.: PUS-E005-013

CERTIFICATE OF TRANSMISSION UNDER 37 CFR §1.8. I hereby certify that this correspondence is being facsimile transmitted to the Patent and Trademark Office

On 29 January 2010

Typed or printed name of person signing this certificate: Jasmin Hug

Signature of person signing this certificate: Jasmin Hug

**FAX TRANSMITTAL
OF ISSUE FEE(S) TRANSMITTAL**

Via facsimile to:

001-571-273-2885, to:
Mail Stop ISSUE FEE
Commissioner for Patents
P.O. Box 1450
Arlington, Virginia 22313-1450
U.S.A.

Dear Sirs:

Attached please find a Fee(s) Transmittal Form for the above-identified application.

Authorization is hereby given to charge the required fees, or credit any overpayment to our deposit account No. 50-2621.

Respectfully submitted,

John Moetteli
/s/ John Moetteli

John MOETTELI
U.S. Reg. No. 35,289

Date: January 29, 2010

Encl: - Fee(s) Transmittal Form